



Form PTO-1449 (REV. 1/06)  US Dept. of Commerce PATENT & TRADEMARK OFFICE  INFORMATION DISCLOSURE STATEMENT  (Use several sheets if necessary)	ATTY DOCKET NO. 128865	APPLICATION NO. 10/587,268
	APPLICANTS Hiroaki TAKAIWA et al.	
	FILING DATE July 26, 2006	GROUP 2882

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